

Atty Docket No.: 0630.0021C

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the PATENT application of:

Berry et al

Examiner: Le, Thao X.

Serial No.: 09/505,695

Group Art Unit: 2814

Filed: February 17, 2000

For:

Method of Photoresist Ash Residue Removal

COMMISSIONER FOR PATENTS

Washington, D. C. 20231

TRANSMITTAL LETTER

MAR 20 2003

Sir:

Transmitted herewith for filing in the subject application are a Notice of Appeal (1 page), a Petition for Extension of Time (1 page), check #6674 in the amount of \$320.00 for the Notice of Appeal fee; and check #6675 in the amount of \$110.00 in payment of the one-month extension of time fee.

Please charge payment of any additional fees required for the above-identified application or credit any overpayment to Deposit Account No. 05-0460.

Respectfully submitted,

Martin Abramson

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Hand Delivered: March 17, 2003